

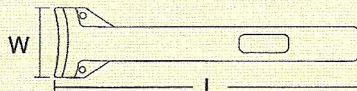
# Manual Wand for Wafer Handling

## Features

- Our unique design (Patent Pending) ensures to handle a delicate and fragile wafer softly but firmly without excessive touch.
- The surfaces of a wafer are never scratched in contrast to conventional metal tweezers.
- The area that contacts wafer surfaces is optically-polished to reduce surface particle counts.

## No metal contamination

- Withstands up to 130°C continuously
- No glue or metal parts

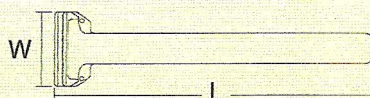
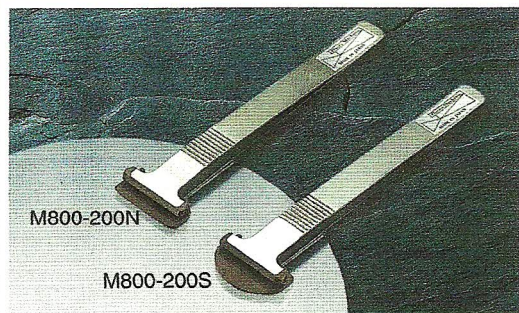


Model	Material	Wafer					Size(mm)		Weight(g)
		4"	5"	6"	8"	12"	L	W	
M100-100	PEEK	●					146	16	30
M100-125			●				148	32	31
M100-150					●		147	37	31
M100-150L					●		185	40	71
M100-200						●	147	37	32
M100-200L						●	180	55	72
M100-300L						●	180	75	77
M110-100	PPS	●					146	16	31
M110-125			●				148	32	32
M110-150					●		147	37	33
M110-200						●	147	37	33
E100-100		Conductive PEEK	●					146	16
E100-125			●				148	32	32
E100-150					●		147	37	32
E100-200						●	147	37	33

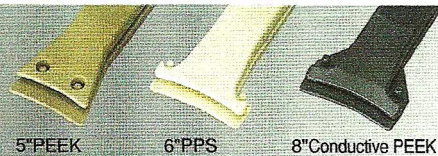
L : Lockable Lever

## For high temperature applications

- Withstands up to 288°C continuously
- Vespel® is firmly glued to SUS (Stainless Steel).



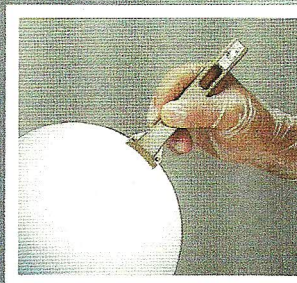
Model	Material	Wafer		Size (mm)		Weight (g)
		6"	8"	L	W	
M800-200N	Vespel+SUS	●	●	154	35	47
M800-200S		●	●	159	35	47



5\"/>

6\"/>

8\"/>



M100-100

M100-125

M100-150

M100-200

M100-200L

M100-300L